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Attorney Docket SEL 231

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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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APR 30 2003
GROUP 1700

In Re Application of)
)
Yamazaki et al.)
)
Serial No.: 09/724,002)
)
Filed: November 28, 2000)
)
For: Film Deposition Apparatus And)
Method Of Manufacturing A Light)
Emitting Device Using The)
Apparatus)
)
Art Unit: 1763)
)
Examiner: K. Moore)

I hereby certify that this correspondence is being
deposited with the United States Postal Service as
first class mail in an envelope addressed to:
the Assistant Commissioner for Patents, Washington,
D.C. 20231 on April 21, 2003
(Date of Deposit)
Shannon Wallace
Name of applicant, assignee, or Registered Rep.
Shannon Wallace 4/21/03
Signature Date

Commissioner for Patents
Washington, D.C. 20231

AMENDMENT B

Sir:

In response to the Office Action dated November 21, 2002, a two month extension of
time being separately requested, please amend the above-identified application as follows:

IN THE CLAIMS:

Please amend the claims as follows:

1. (Previously Amended) A film deposition apparatus comprising:

a stock chamber for loading or unloading a substrata;

a transferring chamber including a mechanism for transferring said substrate; and